

**Notice of References Cited**

Application/Control No.

10/593,809

Applicant(s)/Patent Under

Reexamination

NARAYAN ET AL.

Examiner

JONATHAN C. LANGMAN

Art Unit

1784

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**U.S. PATENT DOCUMENTS**

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-			
B	US-			
C	US-			
D	US-			
E	US-			
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**FOREIGN PATENT DOCUMENTS**

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N					
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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
U	Stavrev et al. "Behavior of thin Ta-Based films in Cu/Barrier/Si system", J. Vac. Sci. Technol. A, Vol. 17, 1999, pgs 993-1001.
V	
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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